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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. 207.007-US)

In the Application of: **LUTZ ET AL.**	) Group) Art Unit: **3683**
Serial No: **10/679,115**	)
Filed: **OCTOBER 3, 2003**	) Before) Examiner: **Mariano Ong Sy**
Title: **FREQUENCY COMPENSATED OSCILLATOR FOR PROCESS TOLERANCE**	)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY OF APRIL 30, 2007

Dear Sir:

This Reply addresses the Office Action of November 1, 2006 (hereinafter, "the Office Action"). In the Office Action, the Examiner maintained the rejection that all of the claims are anticipated by Adams et al., U.S. Patent 5,914,553 ("Adams"). Applicants respectfully disagree. In short, Adams does not describe a microelectromechanical resonator wherein the geometry of the spring mass mechanism is defined such that variations in the effective mechanical stiffness of the spring-mass mechanism are compensated by proportional changes in the effective mechanical mass of the mechanism whereby one or more variations of the fabrication process to the constituent material results in little change to a ratio defined by a change in the effective mechanical stiffness and a change in the effective mechanical mass. Rather, Adams relies exclusively on electrostatic actuators to compensate for variations in fabrication processes -- not any particular geometry.

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